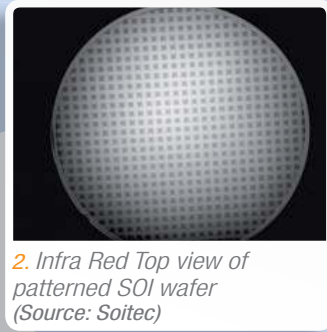
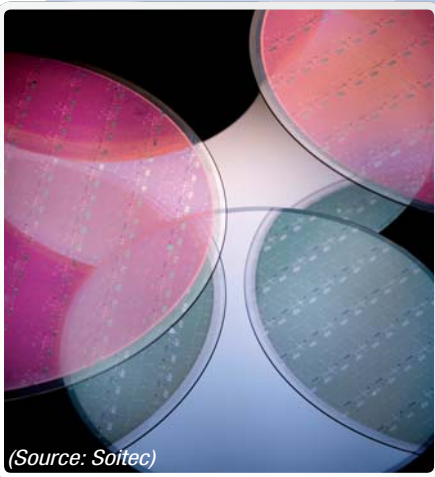
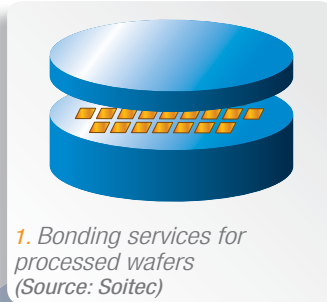


Layer transfer services for embedded functions in customized substrates

For a broad range of applications



Embedding a customized layer onto an application specific substrate (1)

Technical capabilities

- ▶ Based on core Tracit Technologies: direct bonding and thinning techniques
- ▶ Partially processed incoming wafers (implanted, patterned oxide)
- ▶ 150 and 200mm compatible (scalability to 300mm)
- ▶ High and low temperature bonding process capability
- ▶ Compatible with different patterns (from 10µm up to a few mm)
- ▶ Bonding available onto Si, SiO₂, Si₃N₄, fused silica, glass, polycrystalline silicon carbide...
- ▶ Dedicated line for wafer bonding treatment
 - Front-end of the line

Benefits

- ▶ Simplifies device design and manufacturing
- ▶ Hybrid function capability
 - Patterned SOI (2), compatible with thick & thin SOI substrates
- ▶ Hybrid technology integration
 - Open new System-On-Chip (SoC) applications

Device type:

Analog & mixed signal
RF components
Power management IC
Discrete power device
M(O)EMS

End-applications:

Wireless
Medical
Automotive

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